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(54) Title: SUBSTRATE HOLDING DEVICE

(54) 发明名称: 基板保持装置

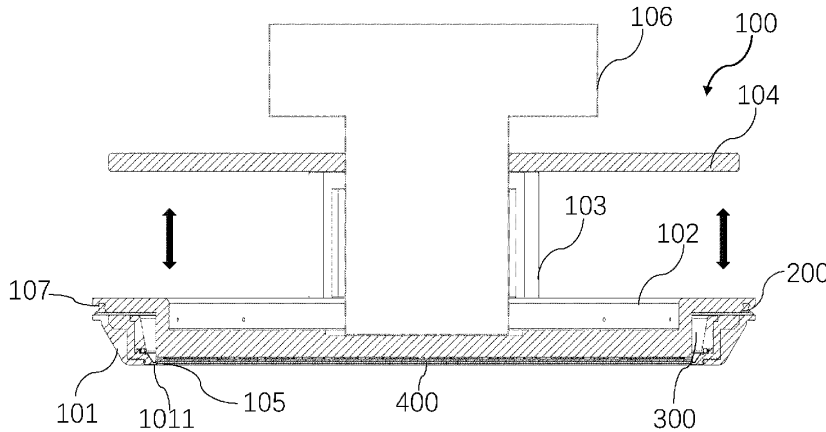


图 1

(57) Abstract: Provided in the present invention is a substrate holding device, comprising: a cup configured to bear a substrate; a pressing disk configured to press against the back surface of the substrate to cause the substrate and the cup to be relatively fixed so as to hold the substrate; a pressing disk driving device connected to the pressing disk and driving the pressing disk to descend or ascend, such that the pressing disk presses the back surface of the substrate to clamp the substrate or the pressing disk moves away from the back surface of the substrate; and a sealing member arranged on the pressing disk and comprising: a fixing portion configured to fix the sealing member on the pressing disk, and a first sealing portion protruding downwards from the fixing portion, wherein the cross-sectional shape of the first sealing portion is the cross-sectional shape of a gap between the peripheral side of the pressing disk and the cup when the pressing disk abuts against the cup, and the first sealing portion abuts against an upper end surface of the cup

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when being pressed by the pressing disk, so as to define a sealing area. In the present invention, multiple seals are formed under the combined action of a first sealing portion, a second sealing portion and a third sealing portion of a sealing member, a sealing effect is further guaranteed, and then the electroplating quality is guaranteed.

(57) 摘要: 本发明提出一种基板保持装置, 包括: 杯体, 被配置为承载基板; 压盘, 被配置为压靠基板背面使基板与杯体相对固定, 以保持基板; 压盘驱动装置, 与压盘连接, 压盘驱动装置驱动压盘下降或上升, 以使压盘压在基板的背面来夹持基板或使压盘离开基板的背面; 密封件, 设置于压盘上且包括: 被配置为将密封件固定在压盘上的固定部; 和从固定部向下凸出的第一密封部, 其中第一密封部的截面形状为压盘与杯体抵靠时, 压盘周侧与杯体之间间隙的截面形状, 第一密封部在被压盘压靠时抵靠杯体上端面以便限定密封区域。本发明通过密封件的第一密封部、第二密封部和第三密封部共同作用下形成多重密封, 密封效果得到进一步的保障, 进而保障了电镀质量。